

## *$A_{Si}-Si_i$ defect as possible origin of electronically activated degradation of boron and indium doped silicon*

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RD50 Meeting, 11.-13.6.14, Bucharest



Forschungsinstitut  
für **Mikrosensorik**  
und **Photovoltaik** GmbH

# Overview

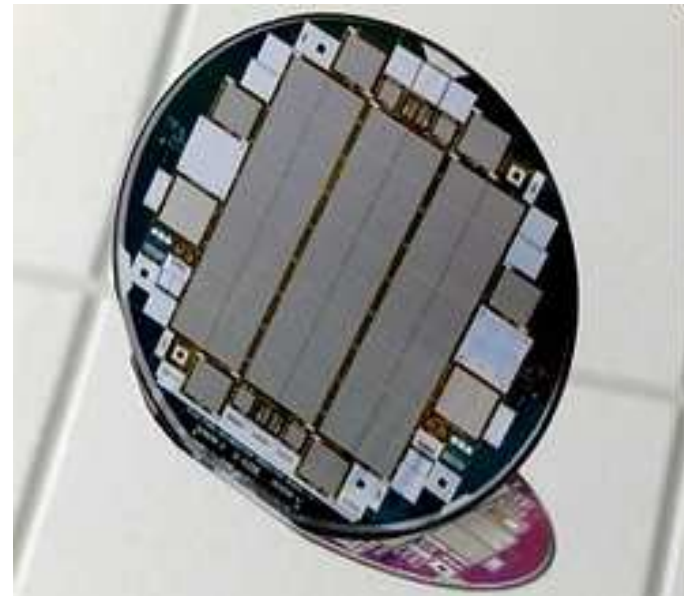
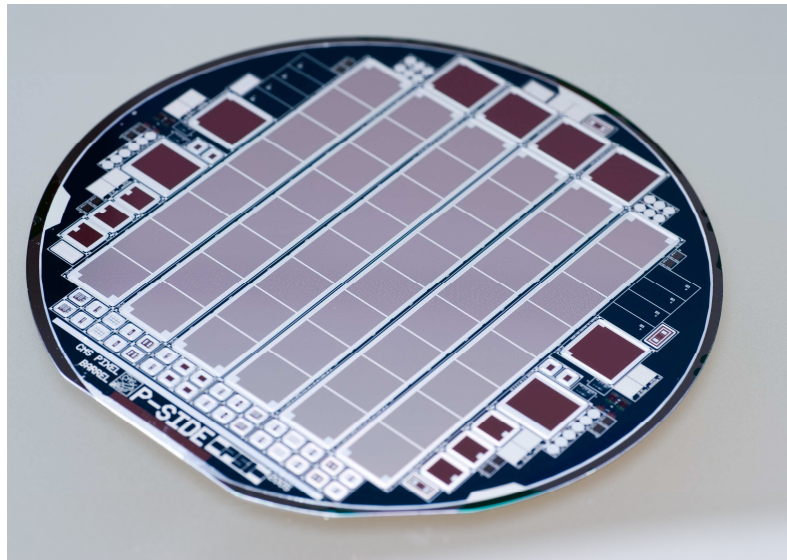


- Recent developments and possibilities at CiS
- Electronically stimulated degradation in boron and indium doped silicon
- $A_{Si}-Si_i$  defect model

# Motivation



- CiS has significantly contributed to sensor productions of various HEP experiments in past and present
  - ATLAS pixel, strips, IBL
  - CMS pixel, strips, CMS upgrade
  - ALICE
  - ...

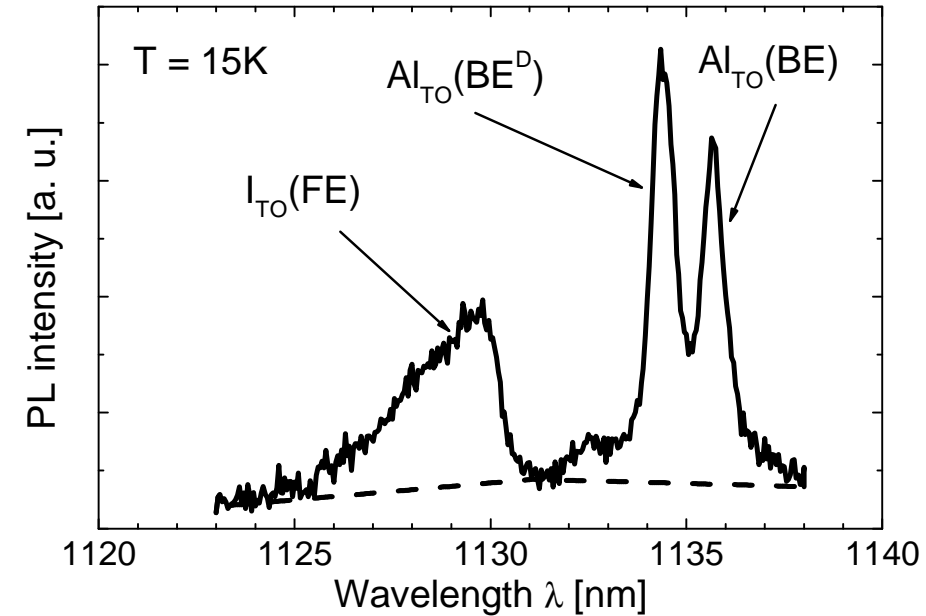
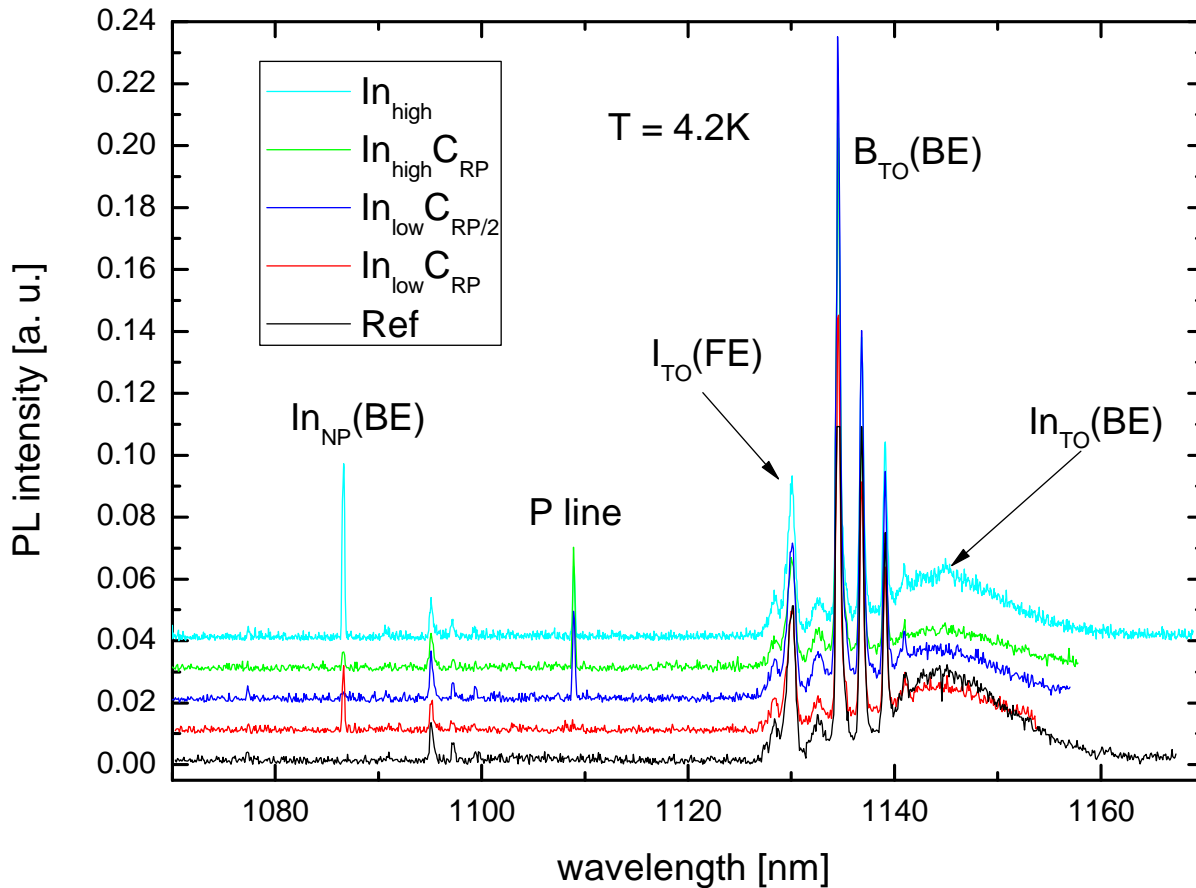


# *Future plans at CiS*



- Foundation of new department “silicon detectors” at CiS
- Synergies from research focused on n-in-p silicon solar cells
- Investigation of defects in silicon radiation detectors
- Methods: Low-temperature PL spectroscopy, low-temperature FTIR, Charge carrier lifetime measurements
- Impact and optimization of defects and defect configurations during detector processing

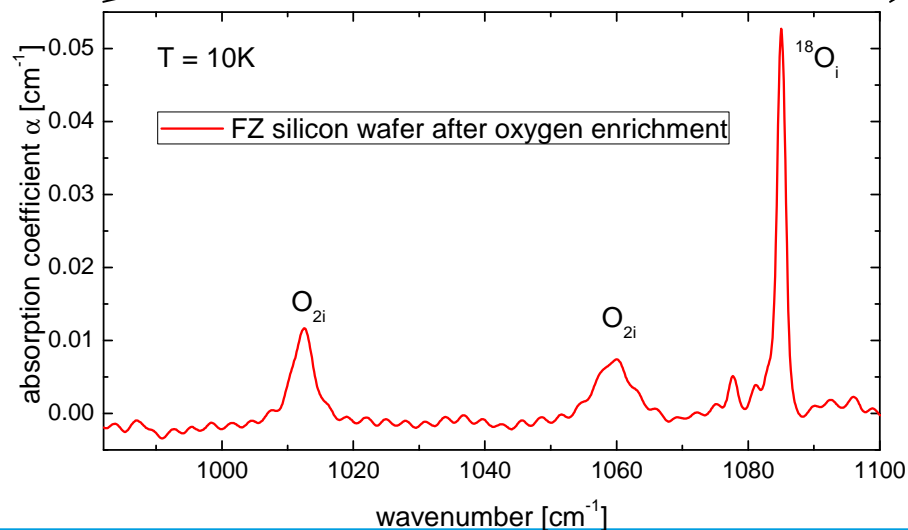
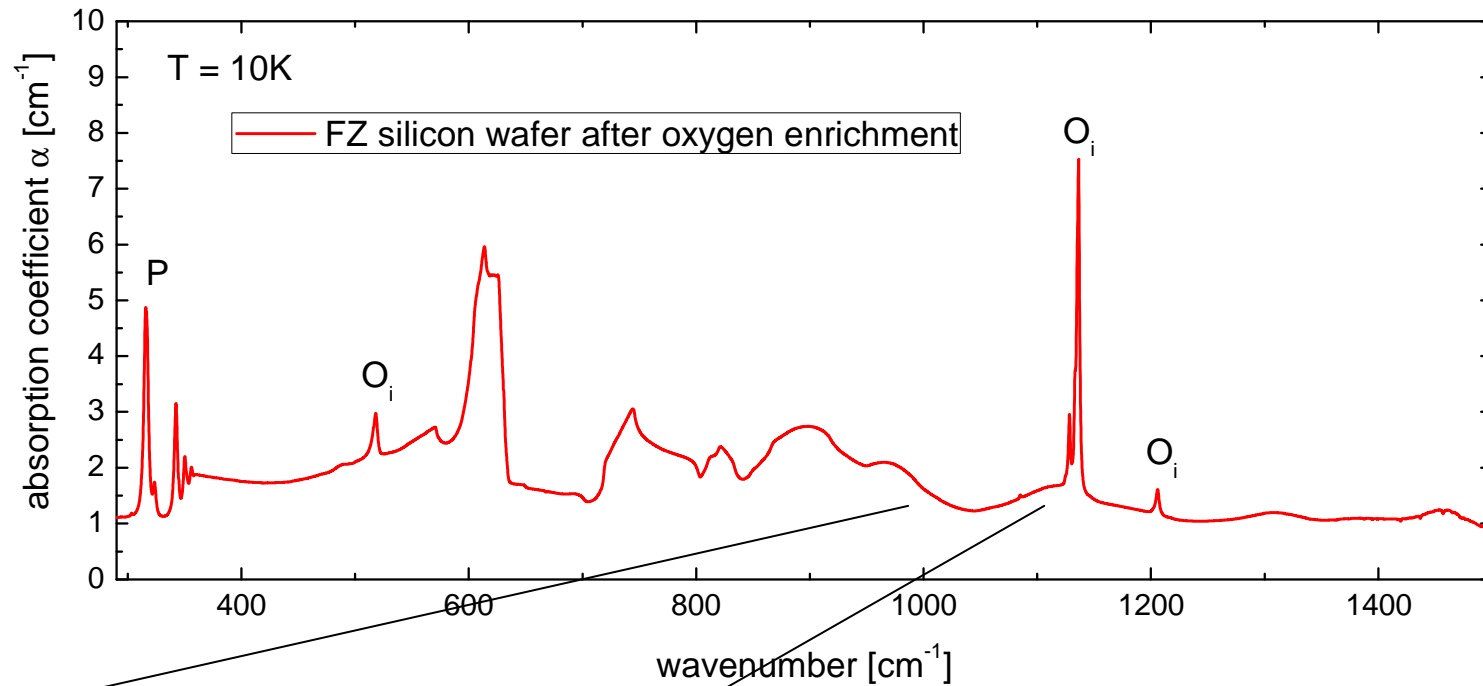
# Low-temperature PL spectroscopy



K. Lauer, C. Möller, D. Schulze, T. Bartel, and F. Kirscht, phys. stat. sol. RRL 7, 265 (2013)

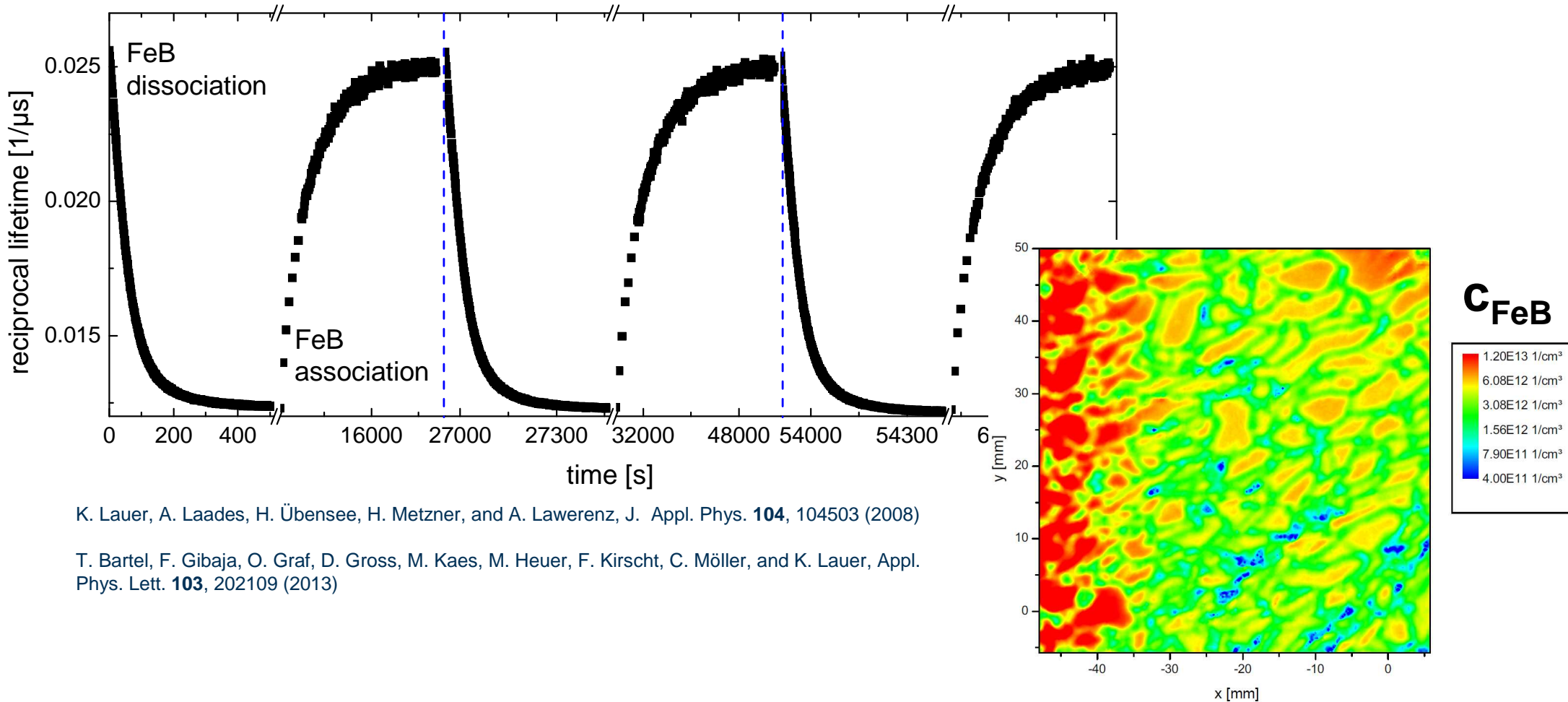
- Defect analysis by LTPL in indium and carbon co-implanted silicon
- Quantification of shallow dopants

# Low-temperature FTIR



- Identification and quantification of defects
- LT-FTIR measured on DOFZ wafers prior to detector processing
- Controlling of defects during processing possible

# Charge carrier lifetime

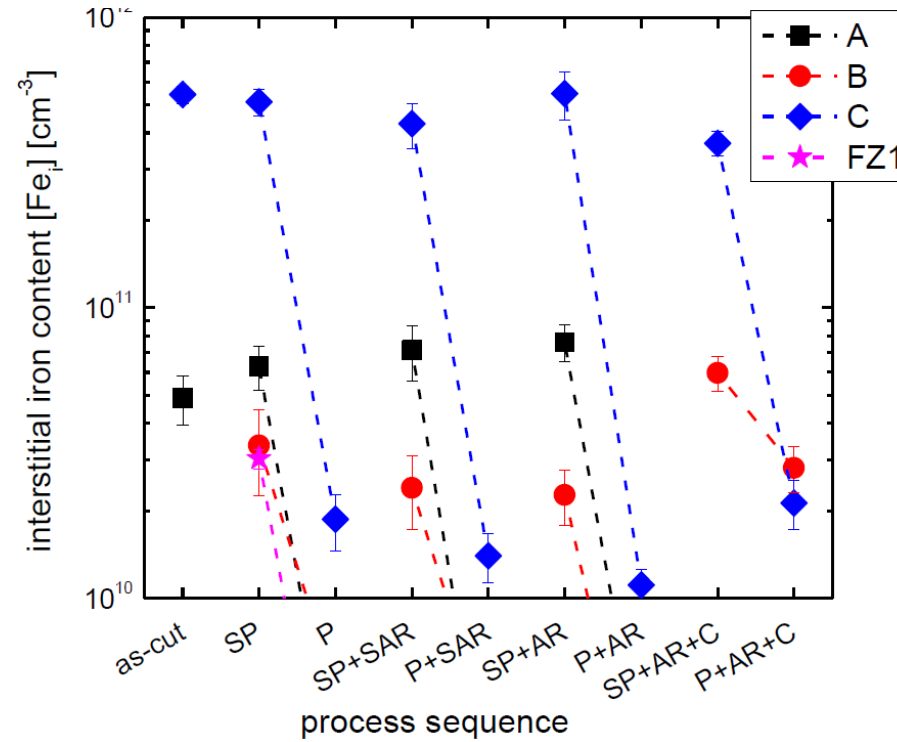
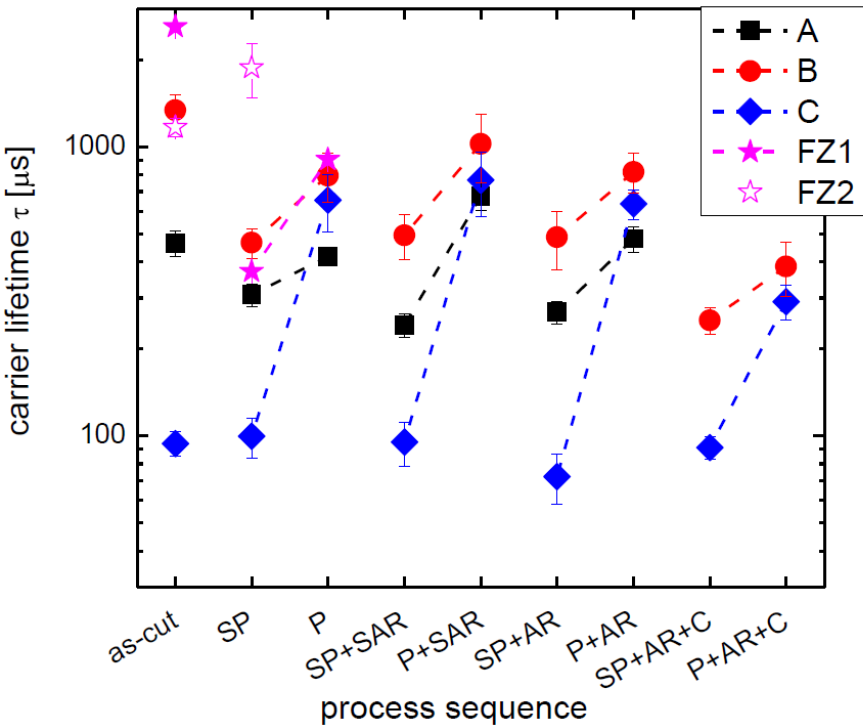


K. Lauer, A. Laades, H. Übensee, H. Metzner, and A. Lawerenz, J. Appl. Phys. **104**, 104503 (2008)

T. Bartel, F. Gibaja, O. Graf, D. Gross, M. Kaes, M. Heuer, F. Kirscht, C. Möller, and K. Lauer, Appl. Phys. Lett. **103**, 202109 (2013)

- Quantification of electrical quality of silicon (spatial and injection resolved)
- Monitoring of defect reactions in silicon
- Iron-acceptor association and dissociation kinetics

# *n-in-p silicon solar cells*



K. Lauer, C. Möller, K. Neckermann, M. Blech, M. Herms, T. Mchedlidze, J. Weber, and S. Meyer, Energy Proc. **38**, 589 (2013)

T. Mchedlidze, L. Scheffler, J. Weber, M. Herms, J. Neusel, V. Osinniy, C. Möller, and K. Lauer, Appl. Phys. Lett. **103**, 013901 (2013)

- Impact of defects on solar cell parameters
- Impact of processing steps on defect properties
- Gettering of impurities by phosphorous diffusion

P ... P-diffusion  
 SP ... thermal budget of P  
 AR ... PECVD SiNx  
 SAR ... thermal budget of AR  
 C ... Contacting





***$A_{Si}-Si_i$  defect?***

# Properties



- Defect known since over 40 years
- First observed in n-in-p solar cells for space application after electron irradiation and subsequent photon irradiation
- Defect degrades charge carrier lifetime in boron doped silicon by electron injection (illumination or forward bias)
- Efficiency of n-in-p solar cells reduced by about 10% due to this defect (commercial problem)
- Possible impact on n-in-p radiation detectors by increasing leakage current (meta stable)

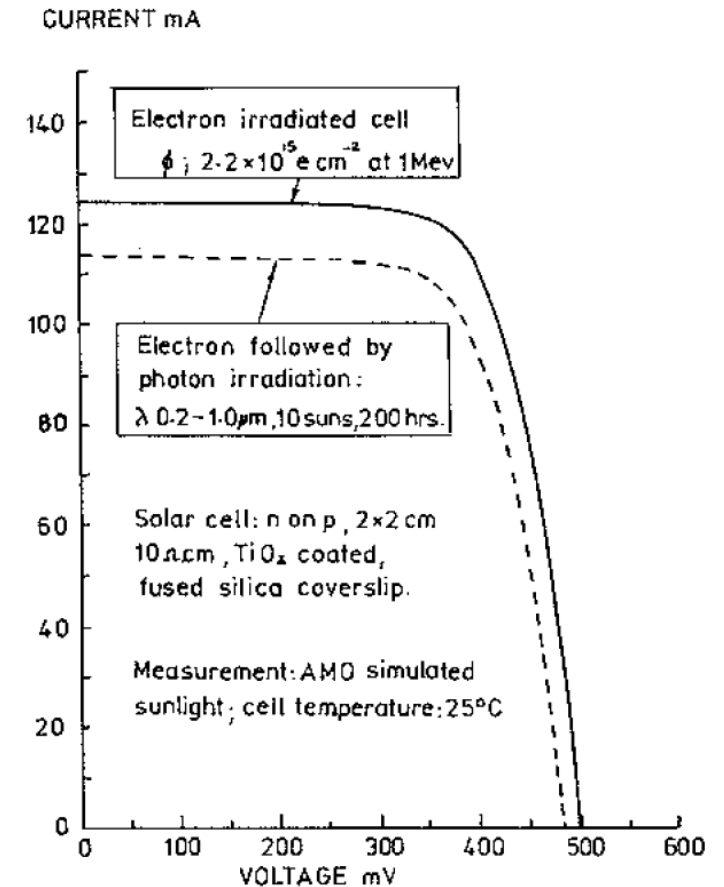


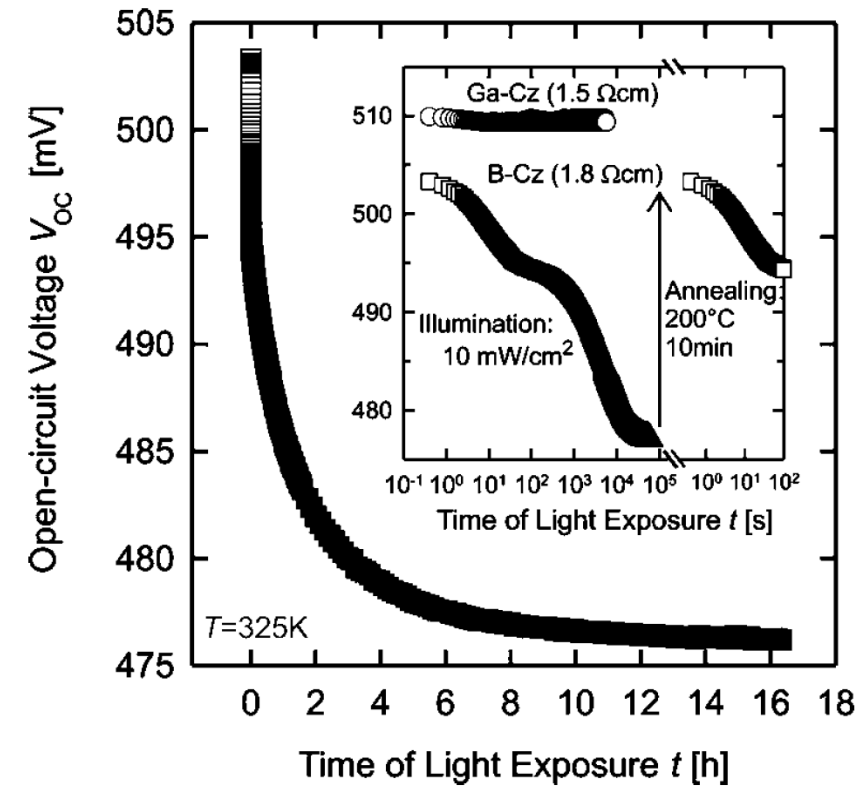
Fig 1 Solar cell V-I performance degradation following sequential electron-photon irradiation

R. L. Crabb, Proceedings of the 9th IEEE Photovoltaic Specialists Conference, New York, 329 (1972)

# Properties

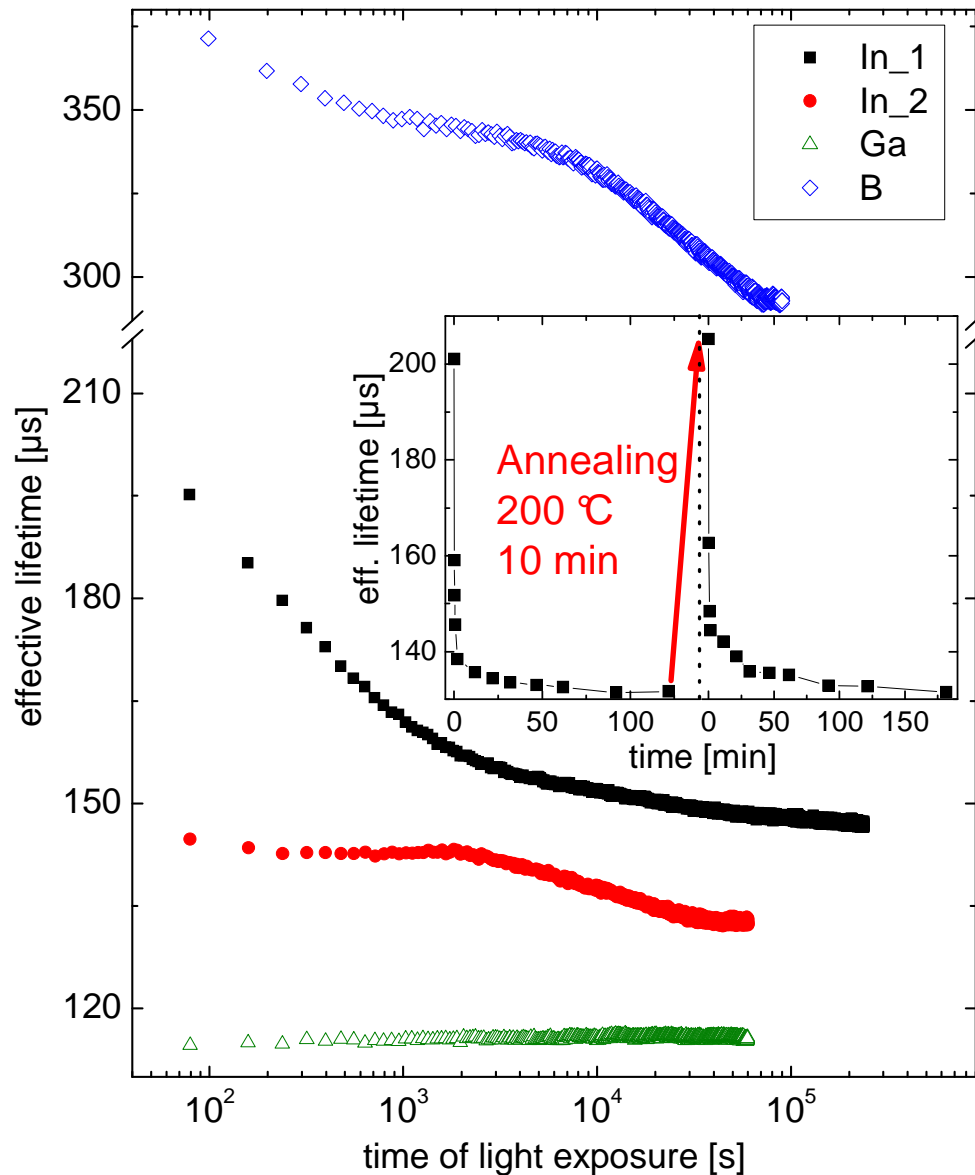


- Appears in as-grown CZ silicon and is reversible
- Does not appear in gallium and aluminum doped silicon
- Depends on oxygen concentration in CZ silicon
- Has fast and slow component
- Depends on hole concentration
- Permanently deactivated by illuminating at elevated temperatures



K. Bothe and J. Schmidt, J. Appl. Phys. **99**, 13701 (2006)

# Degradation in indium doped silicon

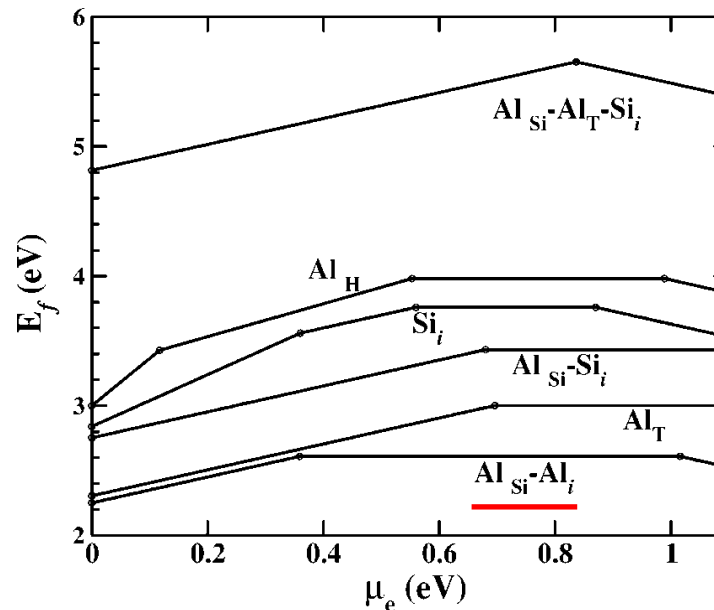
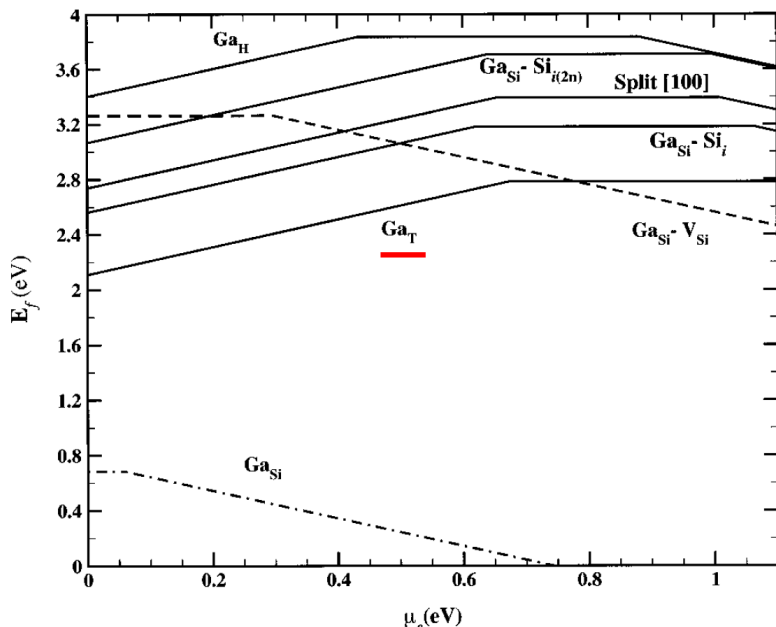
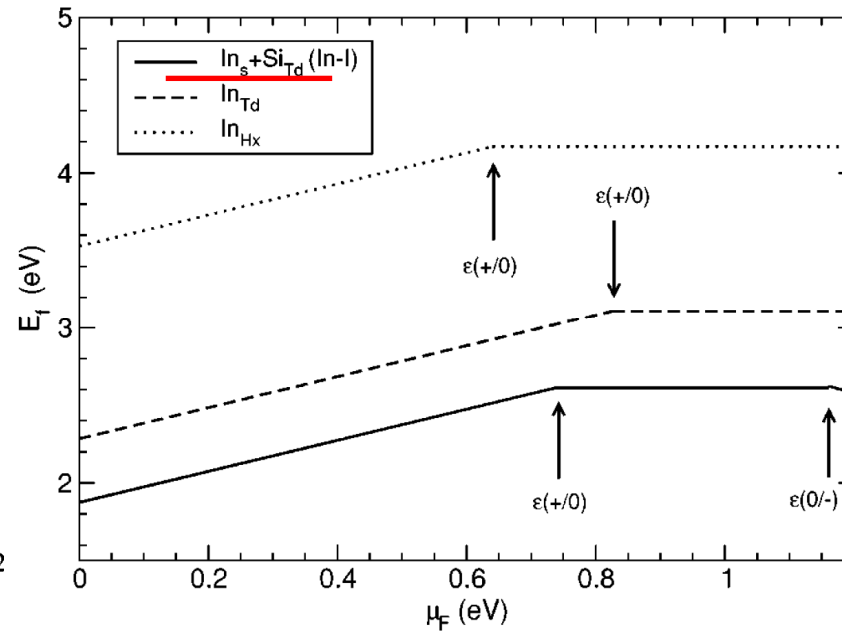
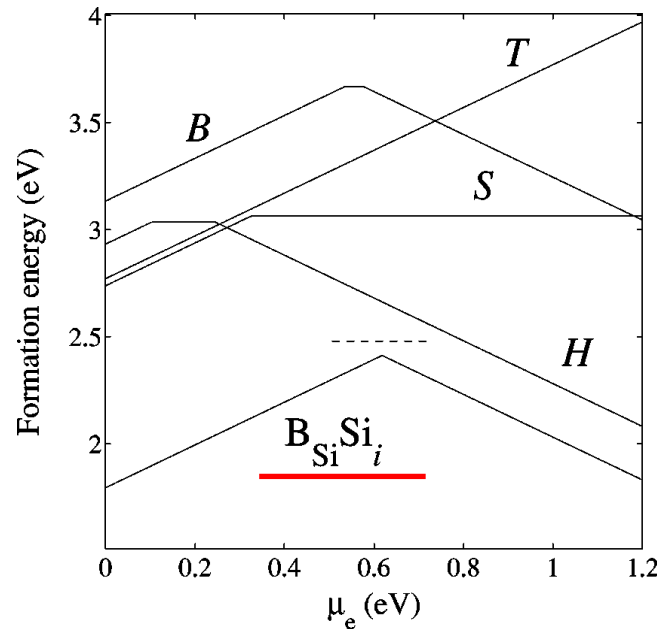


- Defect occurs in indium-doped silicon
- Fast and slow component visible
- Degradation is fully reversible
- Why does the defect occur in boron and indium and not in gallium doped silicon?

sample	method/ orientation	dopant	$\rho$ ( $\Omega$ cm)	$N_A$ ( $10^{15}$ cm <sup>-3</sup> )	$[O_i]$ ( $10^{17}$ cm <sup>-3</sup> )
B	CZ/100	boron	5.80	2.4	9.84
Ga	CZ/100	gallium	3.41	4.1	8.39
In_1	CZ/100	indium	7.82	1.8	17.68
In_2	FZ/111	indium	8.61	1.6	0.11

C. Möller and K. Lauer, phys. stat. sol. RRL 7, 461 (2013)

# Formation energies of interstitial acceptor atoms



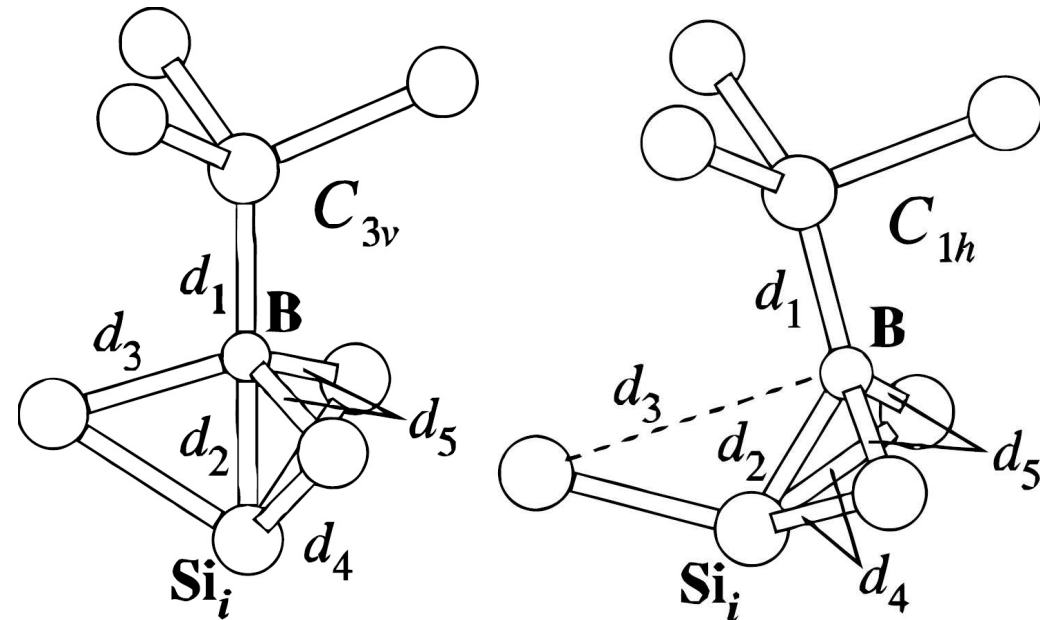
- Configuration of interstitial acceptor atom with lowest formation energy of varies
  - Gallium on tetrahedral position
  - Aluminum forms pair with another Al atom
  - Boron and indium forming an acceptor silicon interstitial pair ( $A_{Si}-Si_i$ )
- =>  $A_{Si}-Si_i$  responsible for observed defect?

Hakala et al., Phys. Rev. B **61**, 8155 (2000)  
 Melis et al., Appl. Phys. Lett. **85**, 4902 (2004)  
 Alippi et al., Phys. Rev. B **69**, 085213 (2004)  
 Schirra et al., Phys. Rev. B **70**, 245201 (2005)

# $A_{Si}-Si_i$ -defect model



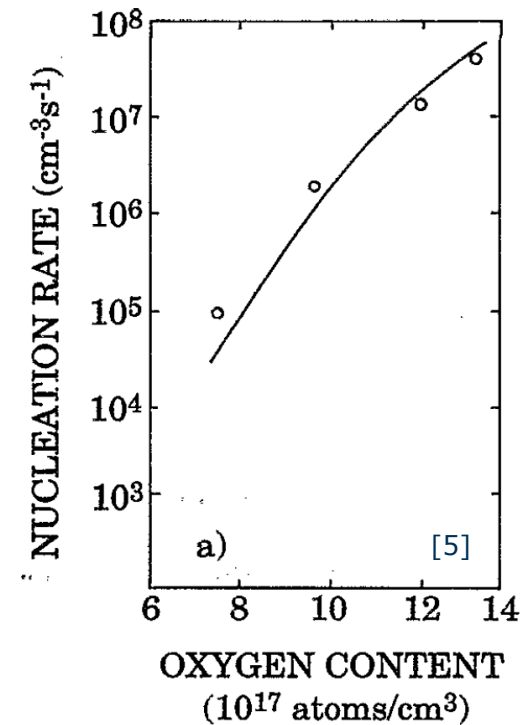
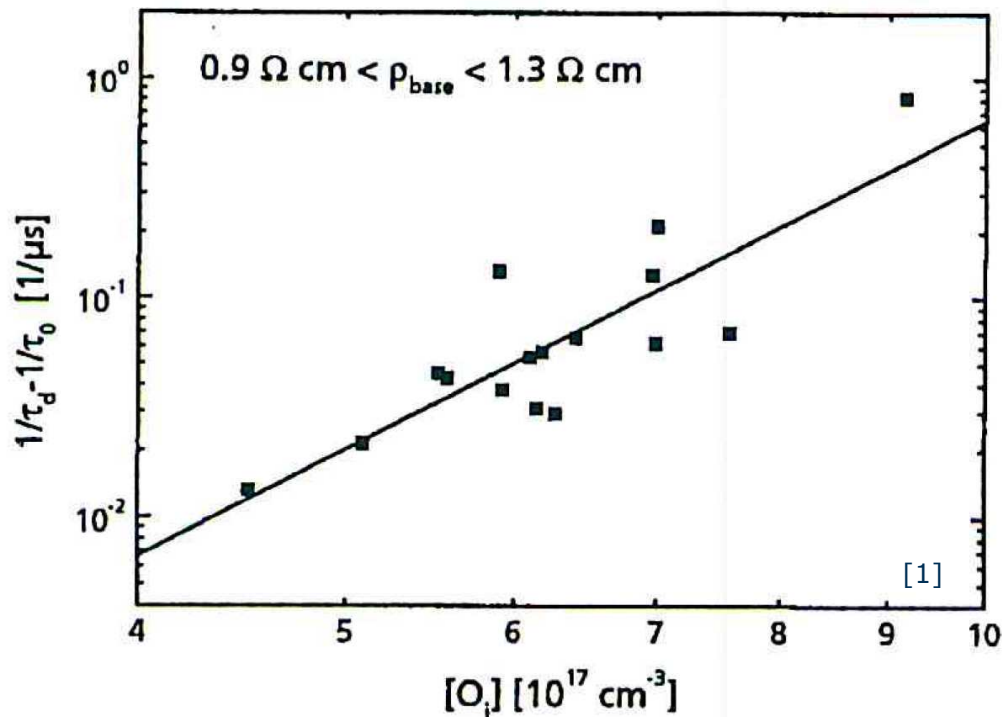
- Configuration in case of boron well investigated by simulation and experiment
- Boron diffusion mediated by this defect
- $A_{Si}$ - $Si_i$ -defect [1] also known as BI defect [2]
- $A_{Si}$ : acceptor atom close to its substitutional position
- Depending on charge state two configurations of defect ( $C_{3v}$  and  $C_{1h}$ ) possible



[1] Hakala et al., Phys. Rev. B **61**, 8155 (2000)

[2] Mirabella et al., J. Appl. Phys. **113**, 031101 (2013)

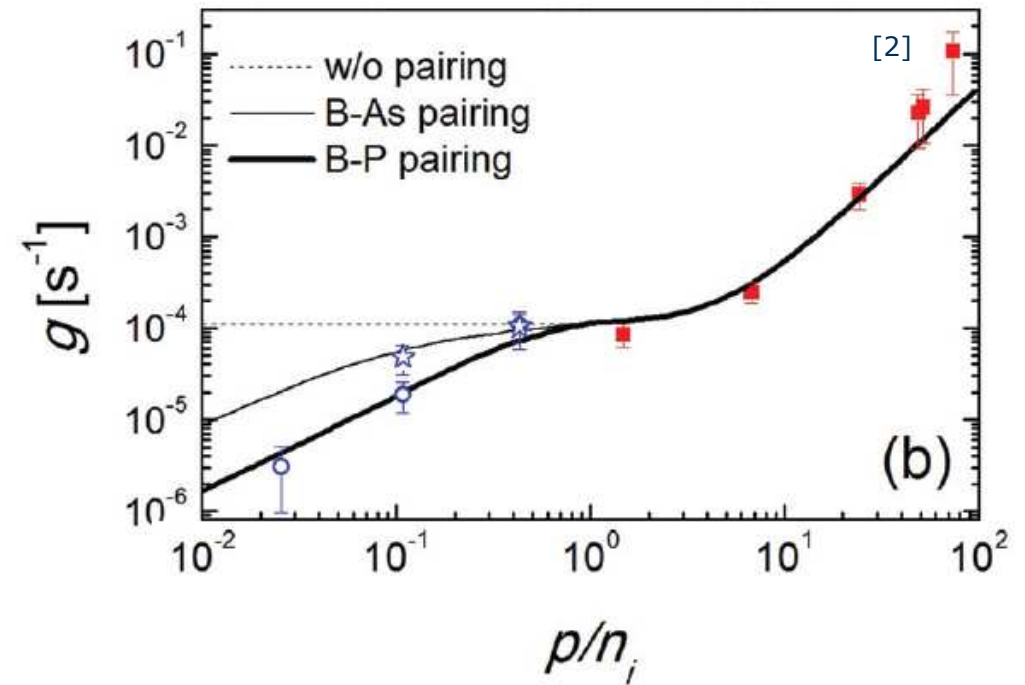
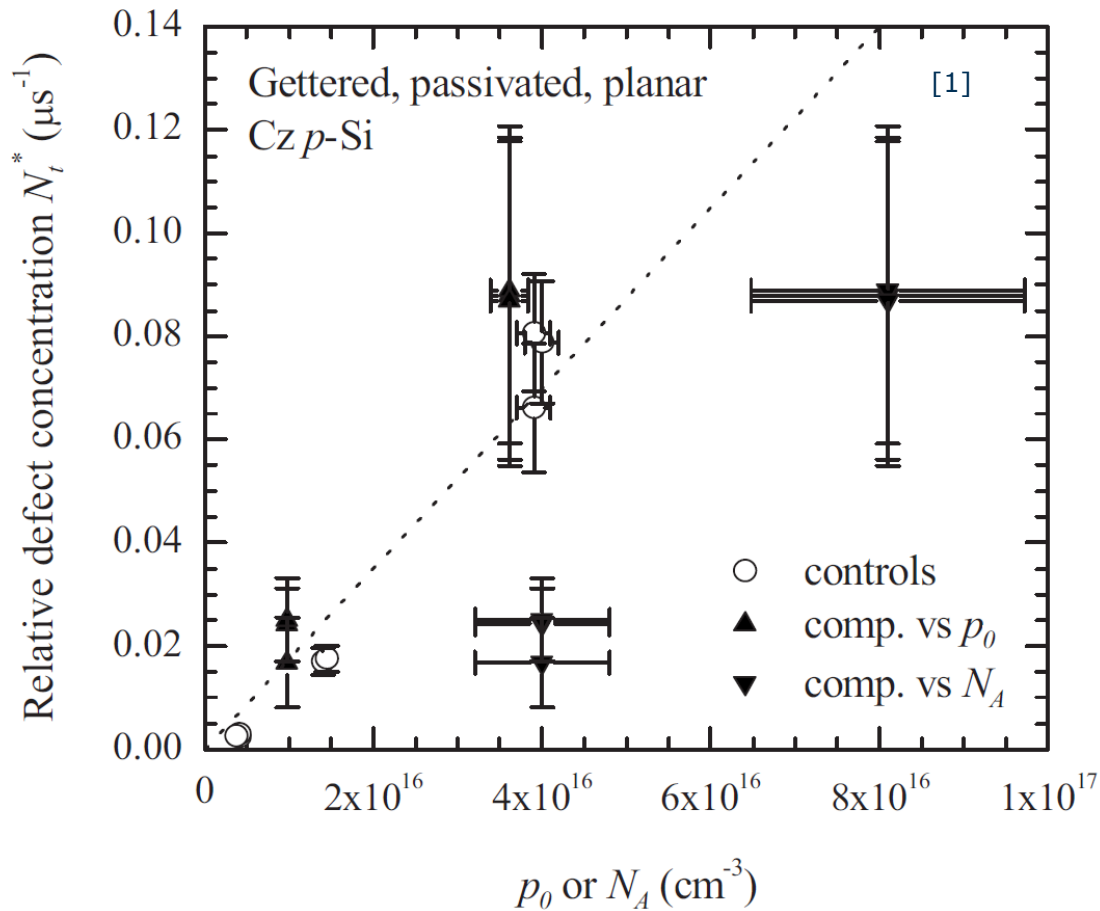
# Dependence on oxygen concentration



- [1] Glunz et al., 2nd WCPVSEC, Vienna, 1343 (1998)
- [2] Gösele, Appl. Phys. A **28**, 79–92 (1982)
- [3] Akhmetov et al. Phys. Stat. Sol. A **72**, 61 (1982)
- [4] Bean et al. J. Phys. C, Solid State Phys. **5**, 379 (1972)
- [5] Borghesi et al., J. Appl. Phys. **77**, 4169 (1999)

- Defect density correlates with interstitial oxygen concentration in CZ silicon (large spread for correlation function in literature)
- $\text{O}_i$  precipitates during CZ crystal cooling ( $2\text{O}_i \rightarrow \text{Si}_i$  [2])
- Defect density and nucleation rate show similar dependence on oxygen concentration [1,5]
- $\text{Si}_i$  migrates to substitutional boron and forms  $\text{B}_{\text{Si}}\text{-Si}_i$  [3,4]

# Dependence on hole-density



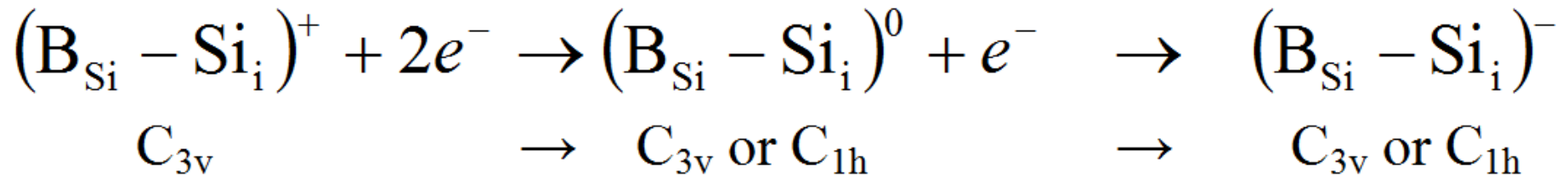
- Defect density is proportional to the hole density [1]
- $\text{B}_{\text{Si}}\text{-Si}_i$  generation rate increases with increasing hole density (measured at 700 °C) [2]

[1] Macdonald et al., J. Appl. Phys. **105**, 093704 (2009)

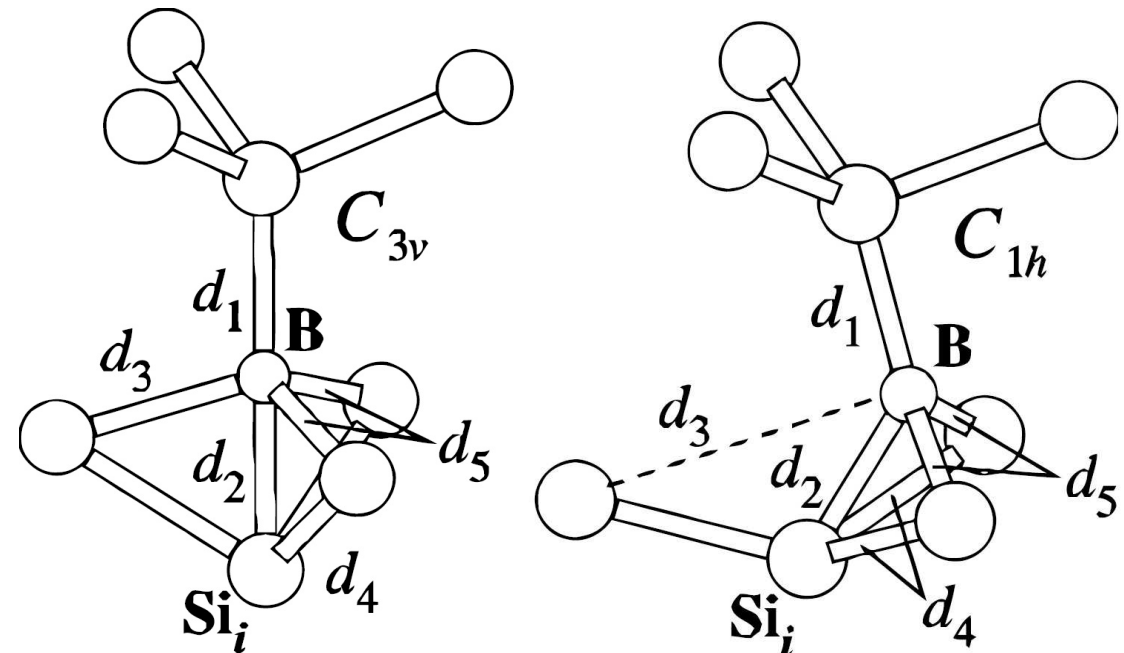
[2] Mirabella et al., J. Appl. Phys. **113**, 031101 (2013)



# Defect kinetic



- Fast process due to trapping of one electron by  $(\text{B}_{\text{Si}} - \text{Si}_i)^+$
- Slow process due to thermal activated change of configuration from  $\text{C}_{3v}$  to  $\text{C}_{1h}$

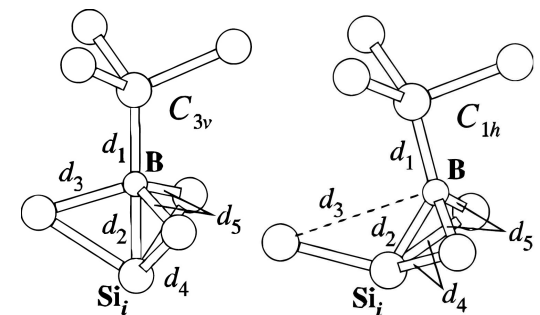


Hakala et al., Phys. Rev. B **61**, 8155 (2000)

# Conclusion / outlook



- LTPL, LTFTIR and carrier lifetime measurements used at CiS for defect analysis
- Investigation of defects during detector processing to realize defect engineering planned
- Degradation of carrier lifetime in boron doped silicon by an electronically activated defect
- Similar defect found in indium-doped silicon
- Defect model proposed based on an acceptor silicon interstitial pair ( $A_{Si}-Si_i$ )
- Observed properties of defect can be explained by  $A_{Si}-Si_i$ -defect model
- Proof of model is missing
- Maybe possibility to generate defect by electron irradiation and look at the defect using state of the art lifetime measurements?
- Investigating effect of defect on n-in-p radiation detectors





***Thank you for your kind attention!***

Thanks to:

M. Herms

J. Weber

N. Abrosimov (IKZ Berlin)

A. Laades

xμ-Material (03SF0398A )

**SOLAR**VALLEY  
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